

Am ndments to th Specification:

Please replace the paragraph beginning at page 7, line 9 with the following rewritten paragraph:

--Support member 6 made of conductor is fastened around the second dielectrics 5 and slit antenna plate 7 with screws 30 for example as shown in Fig. 3 for supporting the second dielectrics 5 and slot antenna plate 7 on chamber lid 1. Slot antenna plate 7 has rectangular slots 7a as shown in Fig. 3 and has a thickness of 1 to 20 mm for example. Rectangular slots 7a are positioned in accordance with a design made for performing a function of a slot antenna described later.--

Please add the following new paragraph after the paragraph ending on page 7, line 21:

--An insulator dielectric 14 is placed between substrate holder 8 and chamber body 2."

Please replace the paragraph beginning at page 12, line 23 with the following rewritten paragraph:

--Referring to Figs. 7 and 8, a plasma processing apparatus according to a third embodiment is structured with gas channels 7b and 7c provided in a slot antenna plate 7. Slot antenna plate 7 is not supported by the support member as employed in the first and second embodiments, but fixed directly to a chamber lid 1 with screws 30 for example.--